

Therefore, having thus described the invention, at least the following is claimed:

	1	1.	A waveguide comprising:
	2		a waveguide core, and
	3		an air-gap cladding engaging a portion of the waveguide core.
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	1	2.	The waveguide of claim 1, wherein the waveguide core includes at least one
£	2		coupling element.
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	1	3.	The waveguide of claim 1, further comprising:
# U	2		at least one coupling element disposed adjacent to the waveguide core.
Į	1	4.	The waveguide of claim 1, further comprising:
	2		a second waveguide cladding adjacent to the waveguide core.
	1	5.	The waveguide of claim 1, further comprising:
	2		a second waveguide core.



- A device, comprising: 6. 1
- 2 a waveguide having a waveguide core and an air-gap cladding
- engaging a portion of waveguide core. 3
- 1 7. The device of claim 6, wherein the waveguide is included in a microelectronic
- 2 device.
- 8. The device of claim 6, wherein the waveguide is included in an integrated 1
- 2 optical device.
- 1 9. The device of claim 6, wherein the waveguide is included in a photonic crystal
- 2 device.

1	10.	A method for fabricating a waveguide comprising:
2		(a) providing a substrate having a lower cladding layer disposed on the
3		substrate;
4		(b) disposing a waveguide core on a portion of the lower cladding
5		layer;
6.		(c) disposing a sacrificial layer onto at least one portion of the lower
7 ·	,	cladding layer and the waveguide core;
8		(d) disposing an overcoat layer onto the lower cladding layer and the
9		sacrificial layer; and
10		(e) removing the sacrificial layer to define an air-gap cladding layer
11		within the overcoat polymer layer and engaging a portion of the waveguide
12	core.	
1	11.	The method of claim 10, further including:
2		disposing an optical grating layer adjacent to the waveguide core after
3		(b) and before (c).



1	12.	A method for fabricating a device comprising:
2		(a) providing a substrate;
3		(b) disposing a waveguide core on a portion of the substrate;
4		(c) disposing a sacrificial layer onto at least one portion of the substrate
5		and the waveguide core;
6		(d) disposing an overcoat layer onto the substrate and the sacrificial
7		layer; and
8		(e) removing the sacrificial layer to define an air-gap cladding layer
9		within the overcoat polymer layer and engaging a portion of the waveguide
10		core.

1	13.	A system for fabricating a waveguide comprising:
2		(a) means for providing a substrate having a lower cladding layer
3		disposed on the substrate;
4		(b) means for disposing a waveguide core on a portion of the lower
5		cladding layer;
6		(c) means for disposing a sacrificial layer onto at least one portion of
7		the lower cladding layer and the waveguide core;
8		(d) means for disposing an overcoat layer onto the lower cladding layer
9		and the sacrificial layer; and
10		(e) means for removing the sacrificial layer to define an air-gap
11		cladding layer within the overcoat polymer layer and engaging a portion of the
12		waveguide core.